

P8000 Advance Linear Track System High Throughput Coating and Developing

Benefits

- Proven to substantially reduce programming errors
- Upgrade from SVG 8x card cages
- Exercise component for troubleshooting and performing maintenance.
- High throughput coating and developing
- Upgraded ATS arms for improved repeatability

Features

- Process 50 mm 200 mm substrates
- PC Windows-based operating system with smartPro GUI
- Barcode and recipe download capable
- Low turbulence catch cup
- CE mark certifies the system's compliance with EU requirements

Options

- Dispense arm vapor atmosphere to prevent drying
- Custom chemical cabinets
- Top full enclosure
- Dual-size bridging without hardware changeover
- Sub-micron capability
- High performance motors with digital controller for improved uniformity and reliability
- Flood expose
- SECS/GEM compliance
- Contact C&D for more options





The C&D smartPro P8000 Advanced Linear System is a recipe-driven wafer coater and developer, featuring powerful Rabbit Microprocessors and an intuitive graphical user interface (GUI) which provide unprecedented capabilities for linear track systems. The system offers a wide range of functions which include expanded recipe storage, data logging, manual exercise mode, and system networking. The system can be configured with modules for coating, developing, baking, priming, and cooling.



Model P8000 with optional top enclosure.









Proven to substantially reduce programming errors





- Windows-based user-friendly GUI allow for expanded recipe storage, monitoring of process parameters in real time, etc. The ability to monitor process parameters in real time as well as log data errors make failures easy to diagnose.
 - System administration for user management, network connection, and database management.
- Capture various system data and present them on the screen as different types of reports – alarm, event, batch, session, and wafer lost report.
- Easily create virtually unlimited number of recipes.

Exercise component for troubleshooting and performing preventive maintenance

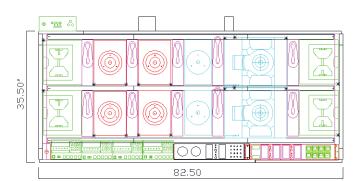
With the P8000 control system, users can manually exercise various modules for troubleshooting and performing preventive maintenance.

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Upgrade from SVG 8X card cage interface

The P8000 is designed to have one control box per track. This compact box is discreetly mounted within the system away from waste and chemical lines. Current SVG users can convert to the C&D P8000 control system with ease. A PC is configured to your system, the card cages removed, and existing cables can plug directly into the C&D control box.

System depicts a two-track P8010 Advanced Linear System. System dimensions vary depending upon configuration.



Available modules	Coater, developer, hot plates, chill plates, vapor prime, and scrubber/lift-off				
Transfer Method	Automatic transfer arm with improved design maintaining end-point placement to within \pm 0.1 mm over 300,000 wafers.				
User Interface	Windows-based operating system with smartPro GUI				
Transfer Mode	Serial transport				
Indexer	SEMI standard H configuration				
Coater	Spin motor: 50 RPM – 9500 RPM in 10 RPM increments (Optional brushless motor with digital controller) # of Dispenses: Up to four Solvent nozzles: Top and bottom EBR				
Developer	Spin motor: 50 RPM – 9500 RPM in 10 RPM increments (Optional brushless motor with digital controller) Stream and spray nozzles				
Hot Plate	Hot plate temperature: Up to 300°C (optional temperature to 400°C) Uniformity: ±0.5% (50°C -300°C) Bake method: Contact or fixed/programmable proximity options				
Chill plate	Standard house chilled water Optional high efficiency chiller at ambient ± .1°C – Option				
Vapor Prime	Temperature range25°C to 190°C Method: Programmable and/or fixed proximity bake capability				
Scrubber/Lift-off	High pressure and brush combination				

Technical Data

www.cdsemi.com